

First Call for Papers

ASPE 2010 Summer Topical Meeting

Precision Interferometric Metrology

June 23-25, 2010

The Crowne Plaza Resort
Asheville, North Carolina

Meeting Co-Chairs:

Chris J. Evans and Peter de Groot
Zygo Corporation

Angela D. Davies
University of North Carolina at Charlotte

The 4th ASPE Topical meeting on Precision Interferometric Metrology will follow the format of its successful predecessors — most recently in Middlefield, CT in 2005 — with meetings in the morning, an evening Open Forum, and an afternoon free to discuss technical details, play sports, walk, shop, or just relax.

Pre-conference visit:

We are planning a visit to the Center for Precision Metrology and the Department of Physics and Optical Science at UNC Charlotte on Tuesday June 22nd; registration will be required.

Speakers are not required to submit full papers (although they are encouraged to do so).

However, they must produce a 1-6 page extended abstract for the PROCEEDINGS.

Registration will be limited to 75 participants.

Please see our web site for additional details on conference location and dates.

For additional information please contact:

American Society for Precision Engineering
301 Glenwood Ave., Suite 205, Raleigh, NC 27603
P.O. Box 10826, Raleigh, NC 27605-0826
Phone (919) 839-8444, or Fax (919) 839-8039

www.aspe.net

Applications such as flat panel displays, IC manufacturing, automotive systems and basic science are driving demand for lower uncertainty measurements in ever more challenging environments. This meeting will cover new developments in interferometric metrology — including new concepts and analyses, instrument development and application examples. In addition to paper sessions, there will be open discussion sessions and opportunities to make brief informal presentations on a variety of topics of interest. The talks will cover a broad range of technologies and highlight potential areas for future development.

The objective of this meeting is to bring together specialists and practitioners from industry, government and academia to provide a forum for the exchange of ideas. The meeting will emphasize discussions as much as the presentations and the participants are encouraged to identify areas needing further research.

Contributed papers are invited, but not limited to, the following relevant topics:

- Tools for form, figure and waviness
- Free form optics and aspheres
- Roughness and texture analysis
- Stage motion control
- Big science projects: Telescope mirrors, space based applications, gravity wave detection
- Interference microscopy
- Micro-structure metrology
- Dynamic measurements
- High precision in adverse environments
- Thin films, patterned surfaces and dissimilar materials
- Lateral resolution beyond conventional limits
- Semiconductor wafer metrology
- Heroic interferometry at the limits of “what can be done”
- Unconventional sources and wavelengths, including UV, DUV, infrared and Terahertz
- Lost arts: Historical techniques enjoying a new life

Submission Deadlines:

April 19, 2010

Final deadline for submission of 400-500 word abstract to ASPE Headquarters.

April 29, 2010

Notification of results of the selection committee to all authors submitting abstracts.

May 31, 2010

Extended 4-6 page abstract due at ASPE Headquarters to be included in the conference PROCEEDINGS.



American Society for Precision Engineering